ABSTRACT

A method of measuring thickness of an optical disc by using an interference effect of the optical disc layer is disclosed. The method includes detecting an intensity of a reflective light according to a wavelength of a light as spectrum data for each wavelength, converting the detected spectrum data for each wavelength into a spectrum value as a function of a wavelength that a refractive index is reflected, and detecting a position where the intensity of the reflective light has a peak as a thickness of a spacer layer and a cover layer respectively by converting the converted value into a length of an interference area for representing a layer thickness of the optical disc by the Fast Fourier Transform. The disclosed method has advantages for high precisely measuring thickness of an optical disc.